

Génie Electrique et Electronique Master Program Prof. Elison Matioli

EE-557 Semiconductor devices I

Metal-Semiconductor Junction

Outline of the lecture

Metal-Semiconductor Junction

- Schottky contacts
- Ohmic contacts

References:

J. A. del Alamo, course materials for 6.720J Integrated Microelectronic Devices, Spring 2007. MIT OpenCourseWare (http://ocw.mit.edu/)

Key questions



- How exactly does current flow happen in a metal-semiconductor junction?
- What are the key dependences of the current in a metal-semiconductor junction?

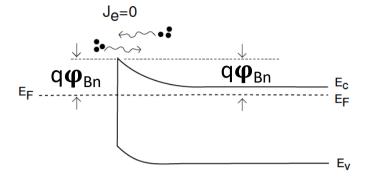


I-V Characteristics

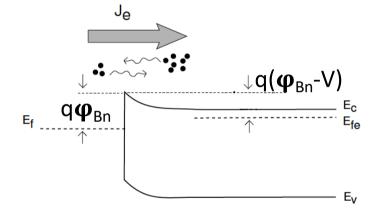
Few minority carriers anywhere
→ majority carrier device

Bottleneck: transport through SCR

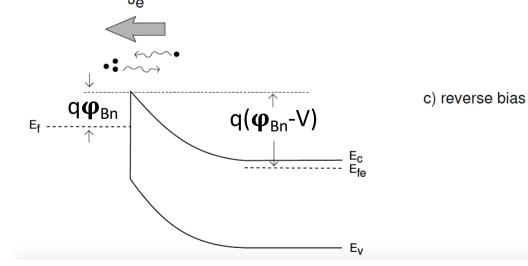
- In reverse bias, J saturates with V



a) equilibrium



b) forward bias





Thermionic-emission theory

Closer than a mean free path from the interface, arguments of drift and diffusion do not work!

In the last mean free path,

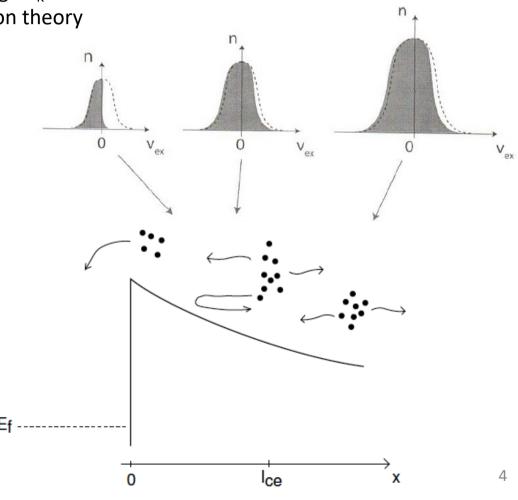
- electrons do not suffer any collisions,
- only those with enough E_{K} get over the barrier.
- actually, only half of those with enough E_K do!
- This is bottleneck: thermionic emission theory

In steady state:

Focus on bottleneck at x = 0:

$$J_t \simeq J_e = -qn(x)v_e(x)$$

$$J = -qn(0)v_e(0)$$





First compute n(0):

n(0) is only a fraction of the carriers present at $n(l_{ce})$:

$$n(0) = \frac{n(l_{ce})}{2} \exp \frac{q[\phi(0) - \phi(l_{ce})]}{kT}$$

If rest of SCR is in quasi-equilibrium

$$n(l_{ce}) \simeq N_D \exp \frac{q\phi(l_{ce})}{kT}$$

$$\phi(0) = -(\phi_{bi} - V)$$

$$n(0) = \frac{N_D}{2} \exp \frac{-q(\phi_{bi} - V)}{kT} = \frac{N_c}{2} \exp \frac{-q(\varphi_{Bn} - V)}{kT}$$

n(0) is exactly half of what one would obtain if its was a bulk semiconductor in TE

All electrons at x = 0 are injected into metal



Then compute $v_e(0)$:

Over the last mean free path, carriers basically travel at v_{th} But, velocity pointing at different angles. After taking care of statistics:

$$v_e(0) = -\frac{v_{th}}{2} = -\sqrt{\frac{2kT}{\pi m_{ce}^*}}$$

(minus sign indicates that electrons are traveling against x) Finally, electron current:

$$J = A^*T^2 \exp \frac{-q\varphi_{Bn}}{kT} \exp \frac{qV}{kT}$$

with

$$A^* = \frac{4\pi q k^2 m_o}{h^3} \sqrt{\frac{(\frac{m_{de}^*}{m_o})^3}{\frac{m_{ce}^*}{m_o}}}$$

 $A^* \equiv \text{Richardson's constant}$



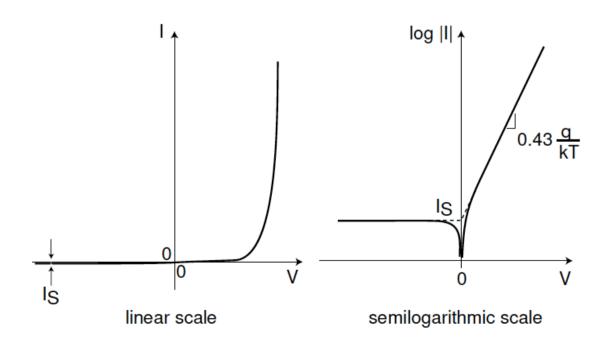
Still must subtract electron injection from metal to semiconductor in TE, so that when $V \rightarrow 0$, $J \rightarrow 0$:

$$J = A^*T^2 \exp \frac{-q\varphi_{Bn}}{kT} (\exp \frac{qV}{kT} - 1)$$

Valid in forward and reverse bias.

$$I_S = A_j A^* T^2 \exp \frac{-q\varphi_{Bn}}{kT}$$

I_s: Saturation current

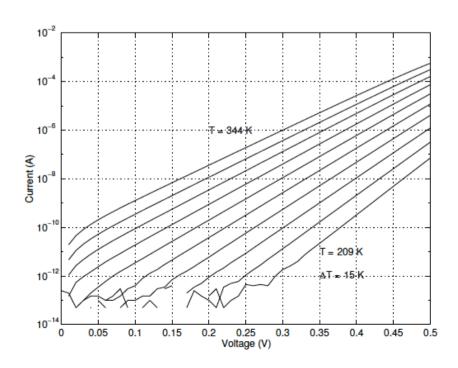


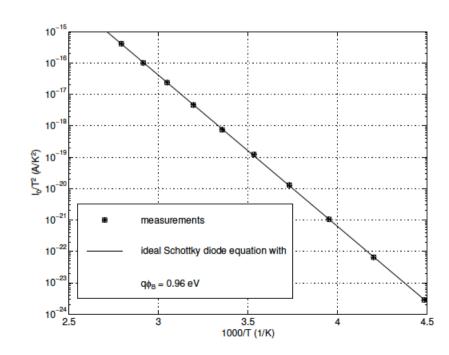


$$J = A^*T^2 \exp \frac{-q\varphi_{Bn}}{kT} (\exp \frac{qV}{kT} - 1)$$

$$I_S = A_j A^* T^2 \exp \frac{-q\varphi_{Bn}}{kT}$$

 I_S/T^2 is thermally activated with activation energy $E_a = q\phi_{Bn}$







Thermionic emission theory valid if: thermionic current << drift current for $I_{ce} \le x \le x_d$.

Bethe condition:

$$l_{ce}|\mathcal{E}_{max}| > 1.5 \frac{kT}{q}$$

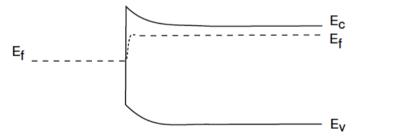
 $l_{ce}|\mathcal{E}_{max}| > 1.5 \frac{kT}{a}$ (Potential drop in the first mean free path > 1.5x thermal potential)

Easily satisfied in Si at around room temperature (mean free paths are rather long).

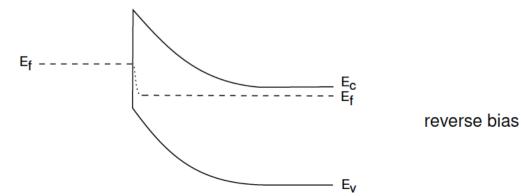
If thermionic emission theory applies:

 E_{fe} flat throughout SCR up to $x = I_{ce}$.

Beyond $x = I_{ce}$, E_{fe} has no physical meaning (electron distribution is not Maxwellian!)



forward bias



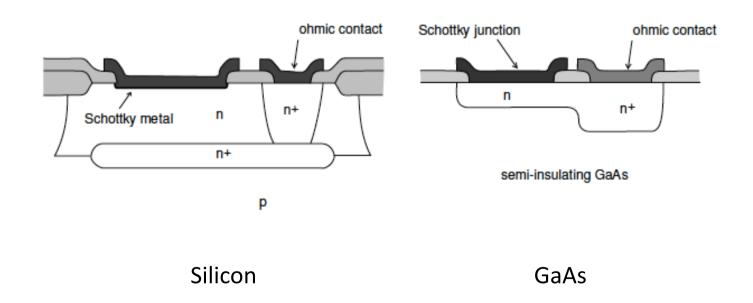


Key uniqueness: fast switching from ON to OFF and back, since it is a majority carrier device

Widely used:

- in analog circuits: in track and hold circuits in A/D converters, pin drivers of IC test equipment
- In communications and radar applications: as detectors and mixers, also as varactors

Typical implementations:

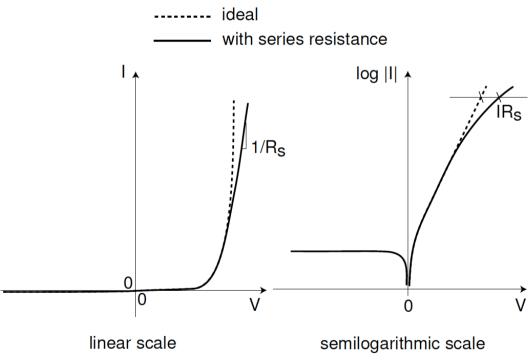




Parasitics

Series resistance due to QNR ohmic drop Voltage across junction is reduced and I-V characteristics modified:

$$I = I_S[\exp\frac{q(V - IR_s)}{kT} - 1]$$



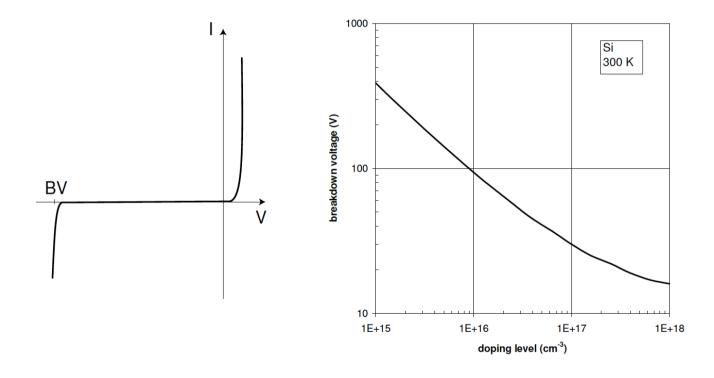
R_s bad because: For given forward current, V increased and harder to control it degrades dynamic response of diode

EPFL

Breakdown

In reverse bias, as $|V| \uparrow \rightarrow |E_{max}| \uparrow$

At a high-enough voltage, avalanche breakdown takes place → breakdown voltage



For moderate doping levels, BV function of N_D alone (independent of ϕ Bn):

For similar doping levels, BV is typically smaller than in Schottky diodes: high electric field occurs at the sharp interface of the metal and semiconductor (in pn junctions high fields are inside semiconductors)

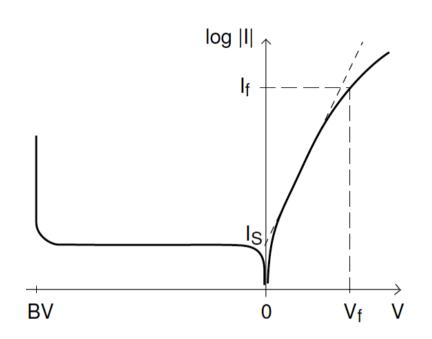


Design issues:

Metal selection:
$$\varphi_{Bn} \uparrow \to V_f \text{ (for fixed } I_f) \uparrow \\ \to I_S \downarrow \\ \to \text{more } T \text{ sensitivity}$$

Doping level selection:

$$\begin{array}{ccc} N_D \uparrow & \to & R_s \downarrow \\ & \to & C \uparrow \\ & \to & BV \downarrow \end{array}$$



Vertical extension of QNR: minimum value of t required to deliver BV (beyond that, $R_s \uparrow$)

Diode area:

$$A_{j} \uparrow \rightarrow C \uparrow$$

$$\rightarrow I_{S} \uparrow$$

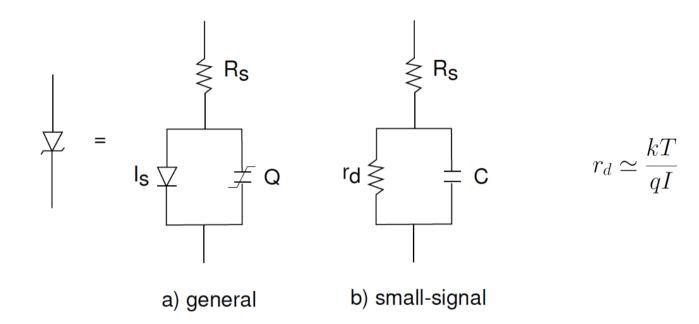
$$\rightarrow R_{s} \downarrow$$

$$\rightarrow V_{f} \text{ (for fixed } I_{f}) \downarrow$$

$$\rightarrow \text{more expensive}$$



Equivalent circuit models



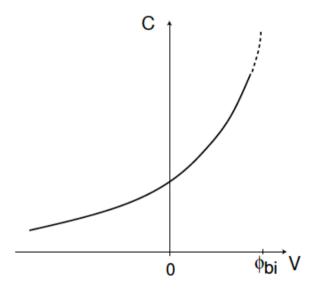
General model:

"Ideal diode" in parallel with capacitor and in series with resistor. Ideal diode is element with exponential I-V characteristics and no capacitances

$$I = I_S(\exp\frac{qV}{kT} - 1)$$



Capacitance in Schottky diodes is much smaller than in pn junctions:



$$C(V) = \frac{\epsilon}{x_d(V)}$$

$$C(V) = \sqrt{\frac{\epsilon q N_D}{2(\phi_{bi} - V)}} = \frac{C(V = 0)}{\sqrt{1 - \frac{V}{\phi_{bi}}}}$$



Equivalent circuit models (real example)

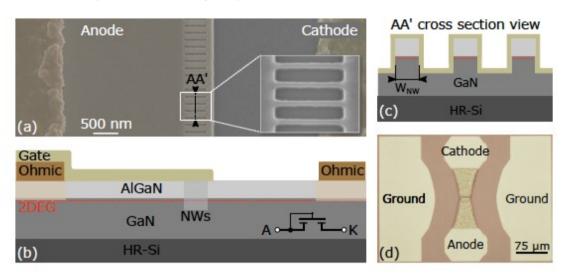
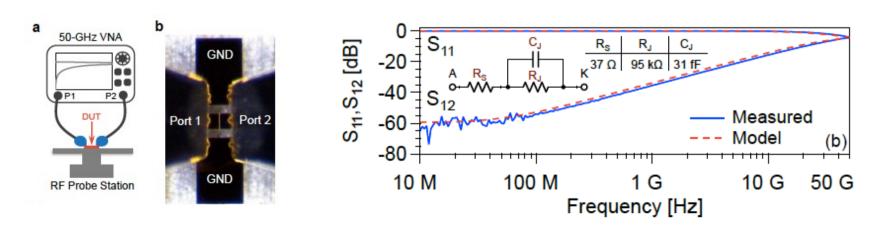


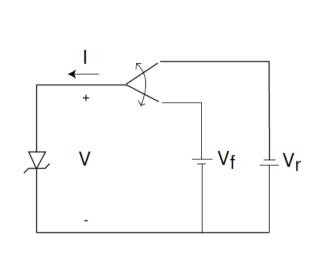
Fig. 1. (a) SEM image of a 30 nm-wide NW-FER. The inset shows the NW array before gate metal deposition. (b) Lateral and (c) cross-section (along AA') schematics of the device. (d) Optical image of a NW-FER showing the ground-signal-ground (GSG) pads for RF measurements.

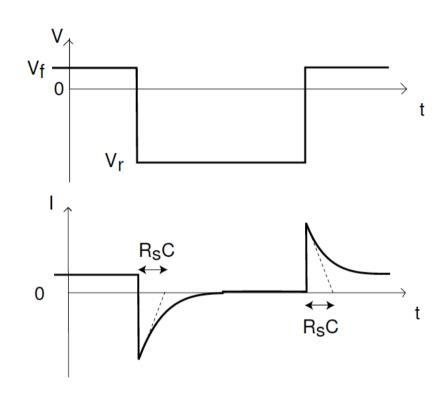




Uniqueness of Schottky diodes: they switch fast!

Large-signal example:



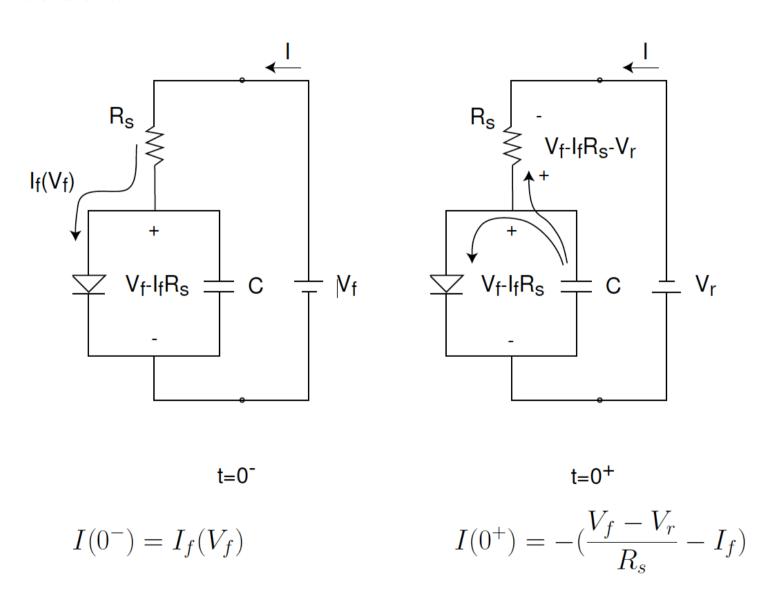


switch-off transient: C charges up through R_s time constant: $\sim R_s C$

switch-on transient: C discharges through R_s time constant: $\sim R_s C$

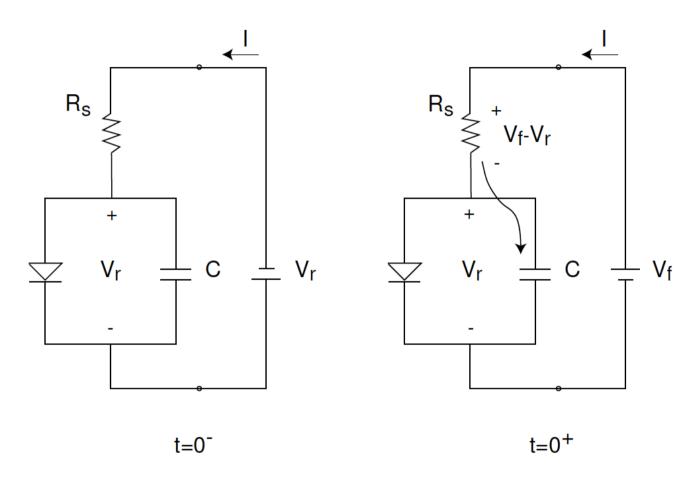


Switch-off transient:





Switch-on transient:



$$I(0^{-}) = -I_s$$

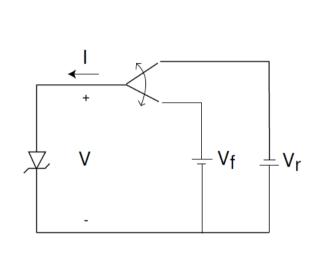
$$I(0^{+}) = \frac{V_f - V_r}{R_s}$$

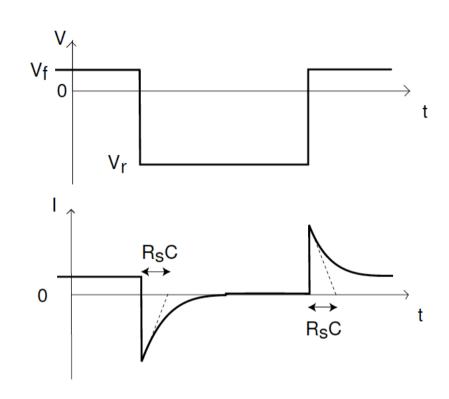
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Uniqueness of Schottky diodes: they switch fast!

Large-signal example:





switch-off transient: C charges up through R_s time constant: ~ R_sC

switch-on transient: C discharges through R_s time constant: $\sim R_s C$

For fast switching \Rightarrow minimize R_s and C

Ohmic contact



Ohmic contacts: means of electrical communication with outside world.

- Key requirement: very small resistance to carrier flow back and forth between metal and semiconductor.
- Can support substantial currents in both forward and reverse biases.
- Achieved by highly doping the semiconductor at the metal interface
- Ohmic contact = MS junction with large J_S
- V small → linearize I-V characteristics:

$$J \simeq A^* T^2 \exp \frac{-q\varphi_{Bn}}{kT} \frac{qV}{kT} = \frac{V}{\rho_c}$$

Figure of merit for ohmic contacts:

 $\rho_c \equiv$ ohmic contact resistivity ($\Omega \cdot cm^2$)

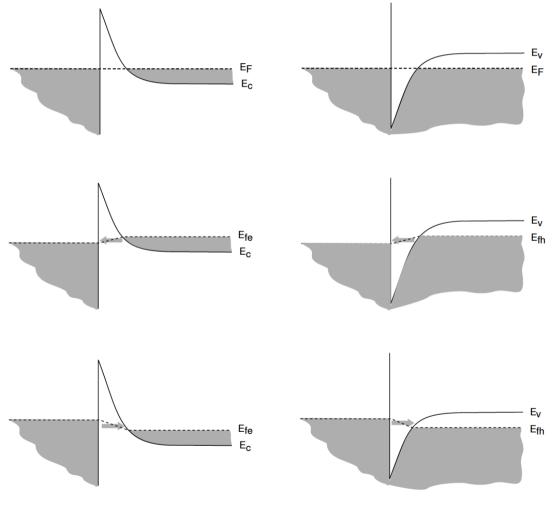
Good values: $\rho_c \leq 10^{-7} \ \Omega \cdot cm^2$

Ohmic contact



How does one make a good ohmic contact?

- Classically, use metal that yields small $q\phi_{Bn}$
- Increase N_D until carrier tunneling is possible



Ohmic contact resistance:

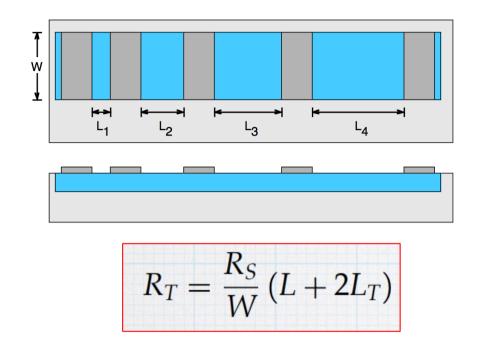
$$R_c = \frac{\rho_c}{A_c}$$

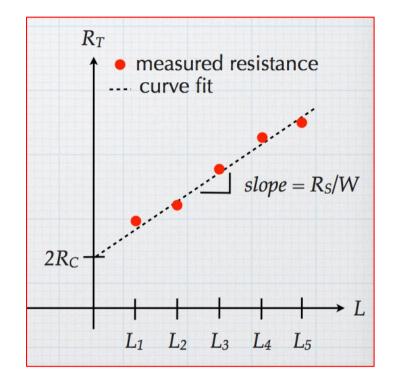
$$A_c \uparrow \Rightarrow R_c \downarrow$$

Lateral ohmic contact

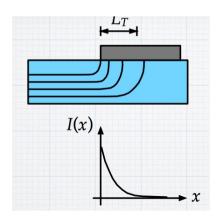


Transmission line measurement (TLM)





At the edge of the contact, the current flowing in (or out) is significant. Moving away from that edge, the current drops off until, at the far edge, there is no current: current crowding



L_T is the transfer length

$$L_T = \sqrt{\frac{\rho_C}{R_S}}$$

The effective area of the contact can be treated as L_TW :

$$R_C = \frac{\rho_C}{L_T W} = \frac{R_S L_T}{W}$$

Key conclusions



Minority carriers play no role in I-V characteristics of MS junction.

Energy barrier preventing carrier flow from S to M modulated by V, barrier to carrier flow from M to S unchanged by $V \Rightarrow$ rectifying behavior:

$$I = I_S(\exp\frac{qV}{kT} - 1)$$

Drift-diffusion theory of current exhibits several dependences observed in devices, but fails temperature dependence.

Thermionic emission theory of current: bottleneck is flow of carriers over energy barrier at M-S interface. Transport at this bottleneck is of a ballistic nature.

 I_S/T^2 is thermally activated; activation energy is $q\phi_{Bn}$.

Ideal BV of Schottky diode entirely set by doping level.

No minority carrier storage in Schottky diode ⇒ fast switching.

Dominant time constant of Schottky diode: R_sC.

Good ohmic contacts fabricated by increasing doping level \Rightarrow carrier tunneling.

 ρ^c , specific contact resistance (in $\Omega \cdot \text{cm}^2$), in Si at 300K: $\rho_c < 10^{-7} \Omega \cdot \text{cm}^2$